

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended): An apparatus for planarizing a workpiece comprising:
 - a) a web having a face, wherein said face comprises microreplicated structures with fixed abrasives and is positioned adjacent said workpiece during planarization;
 - b) at least one tension assembly configured to maintain tension of said web;
and
 - c) an orbiting assembly configured to orbit said web relative to said workpiece wherein the radius of orbit of the web is less than the radius of the workpiece; and
 - d) a manifold apparatus configured to effect fluid flow to said face of said web.
2. (Cancelled)
3. (Cancelled)
4. (Cancelled)
5. (Cancelled)
6. (Cancelled)
7. (Cancelled)
8. (Cancelled)
9. (Cancelled)
10. (Cancelled)
11. (Cancelled)
12. (Cancelled)
13. (Currently Amended): The apparatus of claim ~~12~~ 1 wherein said web comprises holes through which fluid from said manifold apparatus may flow.
14. (Cancelled)
15. (Cancelled)
16. (Cancelled)
17. (Cancelled)
18. (Cancelled)

19. (Cancelled)
20. (Cancelled)
21. (Cancelled)
22. (Cancelled)
23. (Cancelled)
24. (Cancelled)
25. (Cancelled)
26. (Cancelled)
27. (Cancelled)
28. (Cancelled)
29. (Cancelled)
30. (Cancelled)
31. (Cancelled)
32. (Cancelled)
33. (Cancelled)
34. (Cancelled)
35. (Cancelled)
36. (Previously presented): An apparatus for planarizing a workpiece comprising:
 - a) a plurality of polishing stations wherein at least one of said plurality of polishing station comprises a web with a first face which is positioned adjacent said workpiece during planarization;
 - b) an orbiting assembly configured to orbit said web relative to said workpiece wherein said first face of said web comprises fixed abrasives; and
 - c) a manifold apparatus configured to effect fluid flow to said first face of said web.
37. (Original): The apparatus of claim 36 wherein said first face of said web comprises fixed abrasives.
38. (Original): The apparatus of claim 36 further comprising a drive mechanism for indexing said web a predetermined amount.
39. (Original): The apparatus of claim 38 wherein said web is indexed intermittently during planarization of said workpiece.

40. (Original): The apparatus of claim 38 wherein said web is indexed continuously during planarization of said workpiece.

41. (Original): The apparatus of claim 38 wherein said web is indexed between planarization of a first workpiece and planarization of a second workpiece.

42. (Original): The apparatus of claim 36 wherein said web has a second face and wherein said apparatus further comprises a supporting surface in contact with said second face.

43. (Original): The apparatus of claim 42 further comprising:
a new roll cartridge configured for holding an unused portion of said web and allowing said web to be incrementally drawn under tension and moved over the supporting surface; and

a take-up cartridge for receiving a used portion of said web.

44. (Original): The apparatus of claim 36 further comprising at least one tension device configured to maintain a tension of said web.

45. (Original): The apparatus of claim 36 further comprising a plurality of workpiece carriers, the number of which corresponds to the number of said polishing stations, wherein each of said plurality of workpiece carriers is configured to carry a workpiece and press said workpiece against said polishing station while causing relative motion between said workpiece and said polishing station.

46. (Cancelled)

47. (Previously Presented): The apparatus of claim 36 wherein said web comprises holes through which fluid from said manifold apparatus may flow.

48. (Original): The apparatus of claim 44 wherein said tension device may be adjusted to adjust the tension of said web.

49. (Original): The apparatus of claim 45 wherein said relative motion is selected from the group comprising linear motion, orbital motion, rotary motion, linear and orbital motion, linear and rotary motion, orbital and rotary motion, and linear, orbital and rotary motion.

50. (New): An apparatus for planarizing a workpiece comprising:

a) a web having a face, wherein said face comprises microreplicated structures with fixed abrasives and is positioned adjacent said workpiece during planarization;

b) at least one tension assembly configured to maintain tension of said web;

c) an orbiting assembly configured to orbit said web relative to said workpiece wherein the radius of orbit of the web is less than the radius of the workpiece; and

d) a workpiece carrier configured to carry a workpiece and press said workpiece against said face of said web while the workpiece carrier rotates said workpiece about a vertical axis.

51. (New) An apparatus for planarizing a workpiece comprising:

a) a web having a face, wherein said face comprises microreplicated structures with fixed abrasives and is positioned adjacent said workpiece during planarization;

b) at least one tension assembly configured to maintain tension of said web;

c) an orbiting assembly configured to orbit said web relative to said workpiece wherein the radius of orbit of the web is less than the radius of the workpiece; and

d) a workpiece carrier configured to carry a workpiece and press said workpiece against said face of said web while the workpiece carrier moves said workpiece in an orbital pattern.